



# **Affordable Pre-Finishing of SiC for Optical Applications**

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**Presented by:  
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# **Presentation Outline**

- **Introduction to Create**
- **Background**
- **Innovation**
- **Phase I Results**
- **Phase II Update**
- **Summary**

# Corporate Background

- Founded in 1961
- Contract engineering R&D
  - Fluid dynamics and heat transfer
  - Cryogenics
  - Biomedical
  - Software and data systems
  - Sensors and controls
  - Advanced manufacturing
- Industrial and federal client base
- Technology commercialization
  - Licensing
  - Spin-off companies
  - Custom products
- Spinoffs
  - 9 companies/2000 employees
  - Revenues \$650 M/year

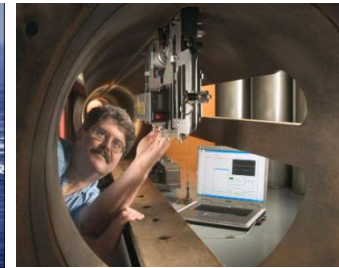
*Aircraft Carrier  
Head/Hearing  
Protection*



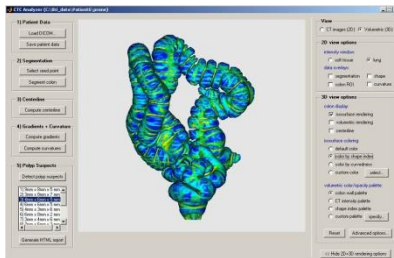
*Cryocooler for Hubble*



*Catapult Gap-Width Measurement Device*



*Miniature High Speed Turbine*



*Image Reconstruction for  
Virtual Colonoscopy*



*Turnkey High-Performance  
Data Acquisition and  
Processing System*



*Anti-Corrosion Coverings*

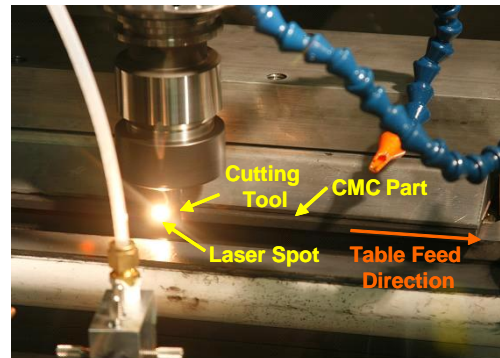




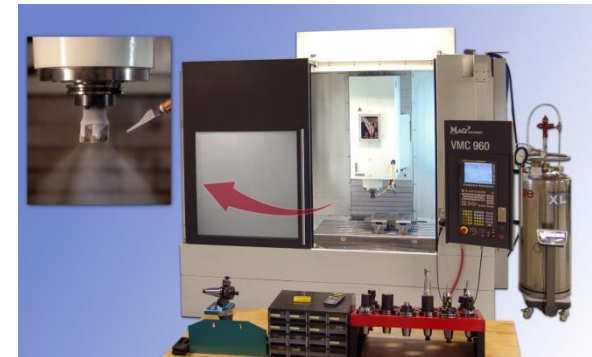
# Advanced Manufacturing at Creare

- Focus on developing new technologies
- Process improvement
  - Cost
  - Quality
- Transition to industrial partners

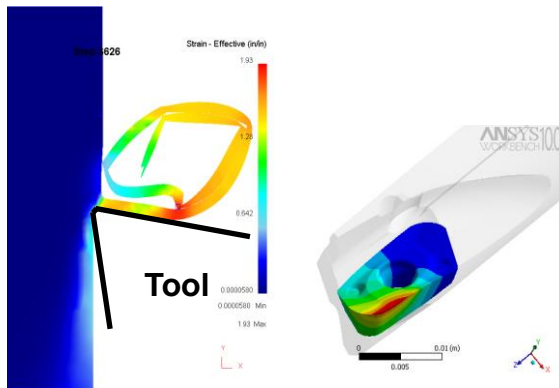
*Laser-Assisted Machining*



*Indirect Cooling*



*Modeling and Simulation*



*Hybrid Processing for Ceramic Mirrors*

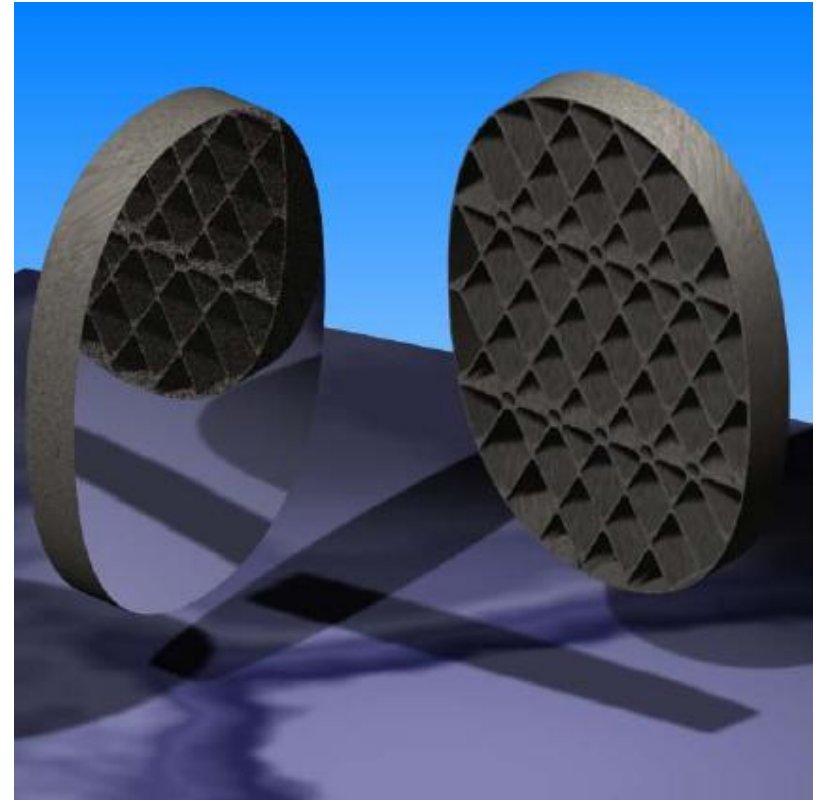


*On-Machine Inspection and Tool Path Correction*



# Silicon Carbide

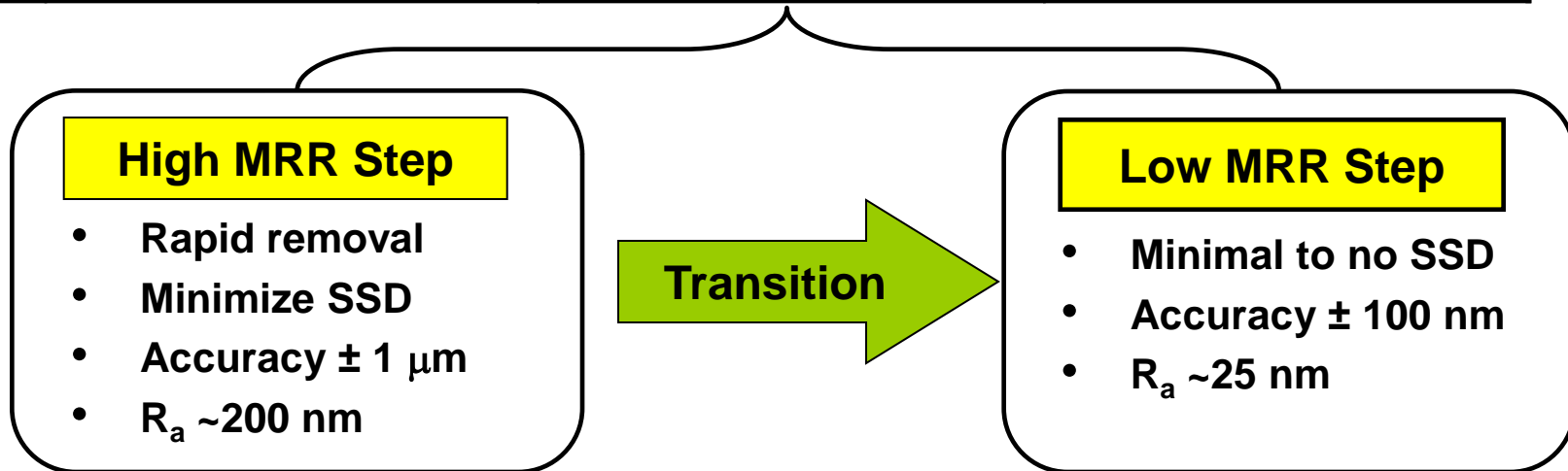
- **Excellent candidate to replace beryllium in lightweight optics**
- **Eliminates toxicity concerns**
- **Lightweight, thermally stable**
- **Cost-effective manufacturing remains a challenge**



# Overall Manufacturing Process

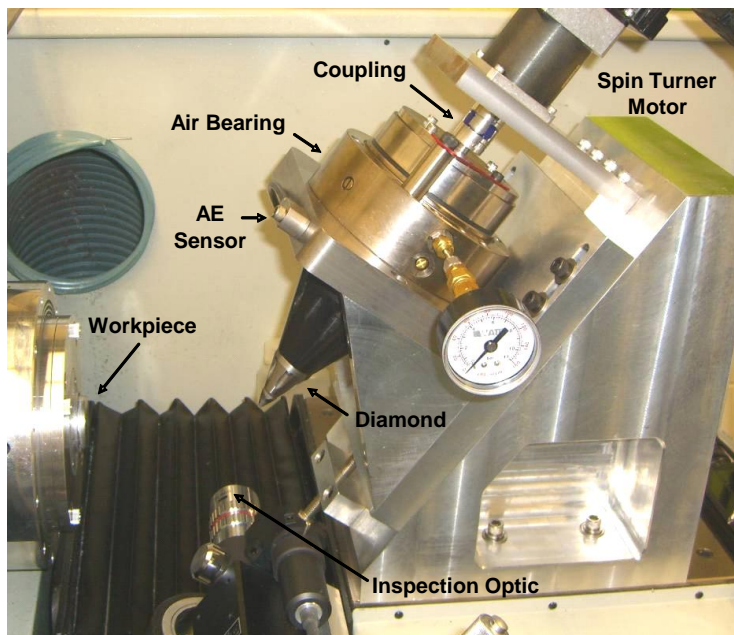


$R_a$	Moderate ( $\sim 2 \mu\text{m}$ )	Low ( $\sim 25 \text{ nm}$ )	Very Low ( $\sim 5 \text{ nm}$ )
Accuracy	$\pm 25 \mu\text{m}$	$\pm 100 \text{ nm}$	$\pm 10 \text{ nm}$
MRR	N/A	High/Low	Low
Process	Single Step	Multiple Steps	Single Step
Cost	\$\$	\$\$\$\$	\$\$

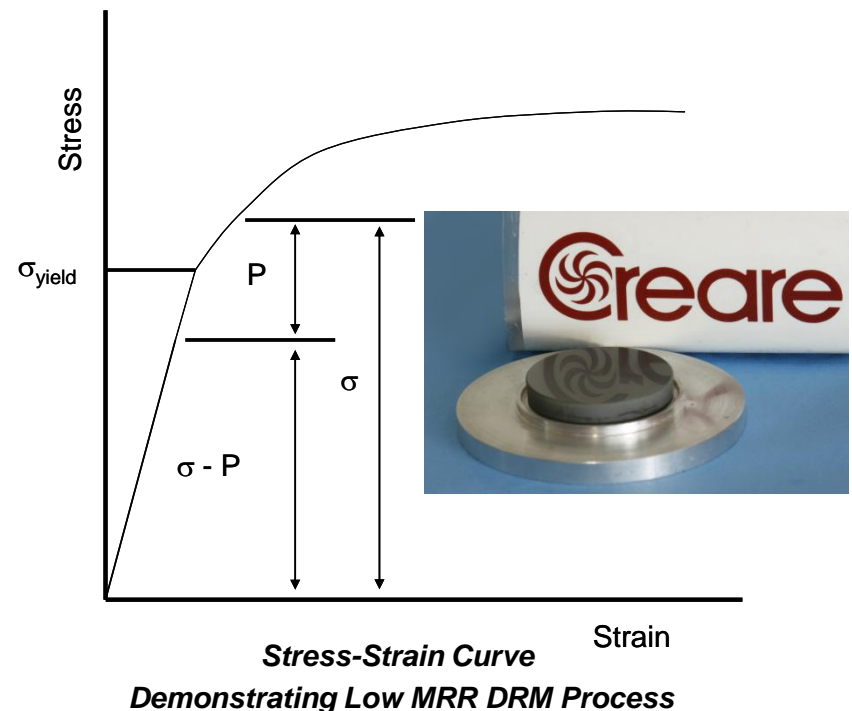


# Our Hybrid Machining Approach

- Use single-point diamond turning (SPDT)
- High MRR process: spin-turning
- Low MRR process: ductile-regime machining (DRM)

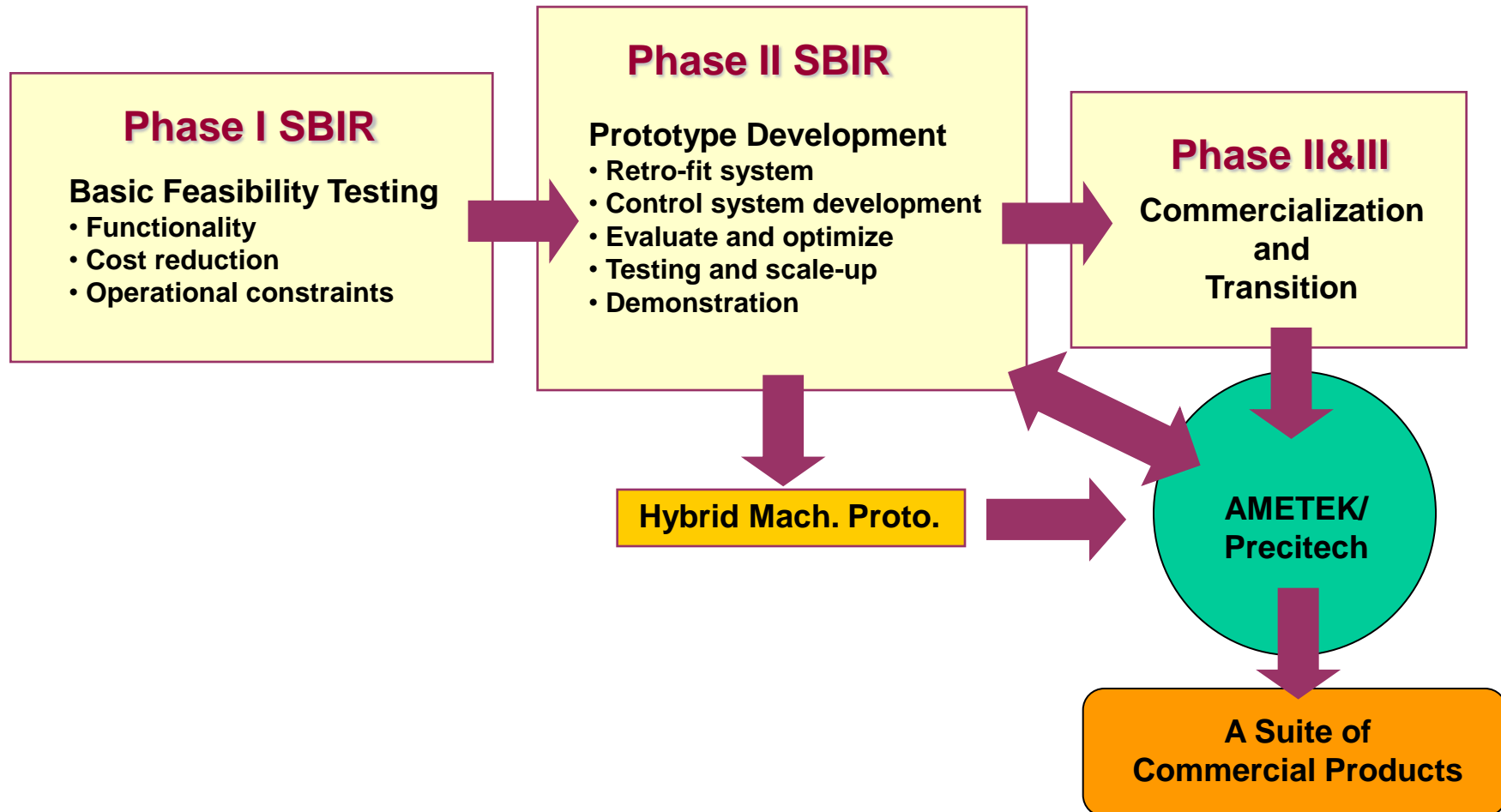


*Spin Turner for High MRR Step*





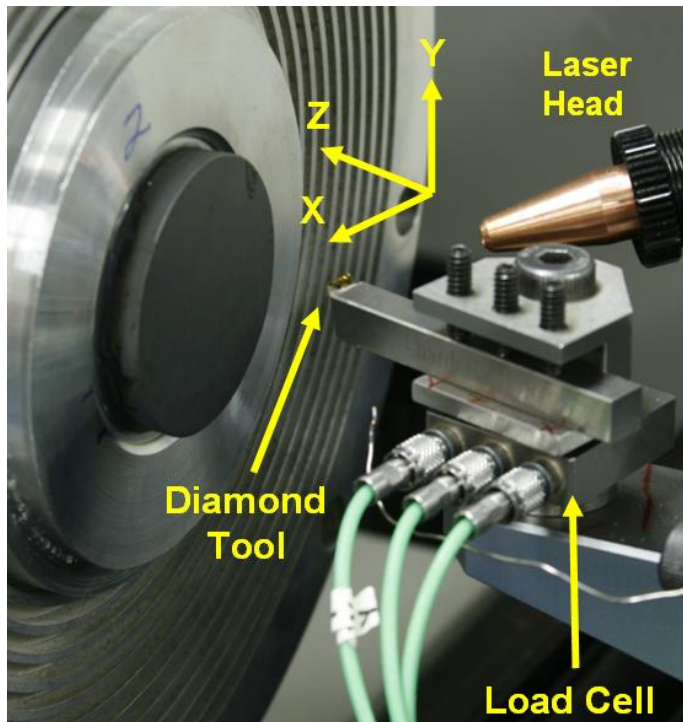
# Program Overview



## Phase I Results

- **Demonstrated feasibility of low MRR DRM on CVD SiC**
  - Successfully machined material to near-optical quality
- **Demonstrated cost savings**
  - Completed detailed cost analysis
  - Showed that other options are as much as 85% higher cost
- **Developed a plan to scale up**
  - Developed the high MRR aspect of the hybrid approach
  - Both based on SPDT
  - Sufficient to machine optics for NASA

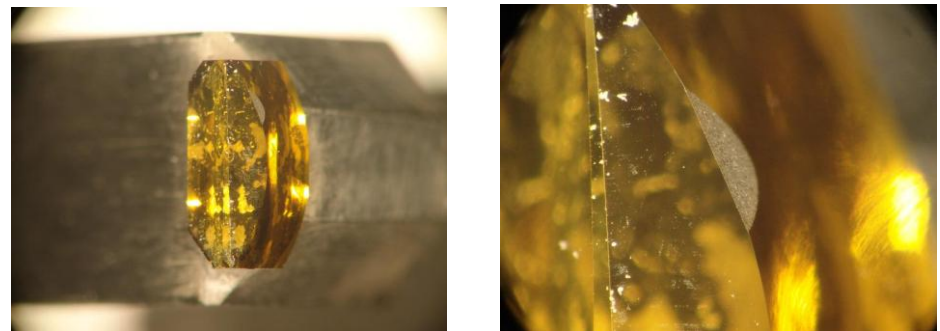
## Phase I Technical Achievements



***Setup for Low MRR Tests***



***Mirror-Like Surface Produced in CVD SiC***



***Tool Wear After ~100 Cuts***

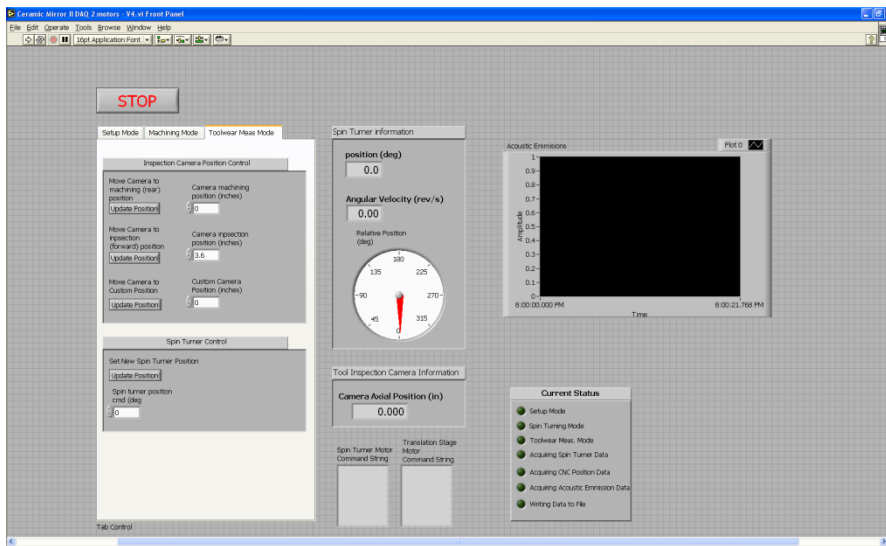
## **Phase II Technical Objectives**

- **Optimize the hybrid machining process**
  - Further develop high MRR process
  - Refine low MRR process
- **Evaluate the performance**
  - Coupled effects
  - Surface quality, part strength
  - Cost savings
  - Scale-up to larger geometries
- **Demonstrate our approach**
  - Machine a representative mirror (~254 mm diameter) from Trex CVD SiC and deliver to NASA

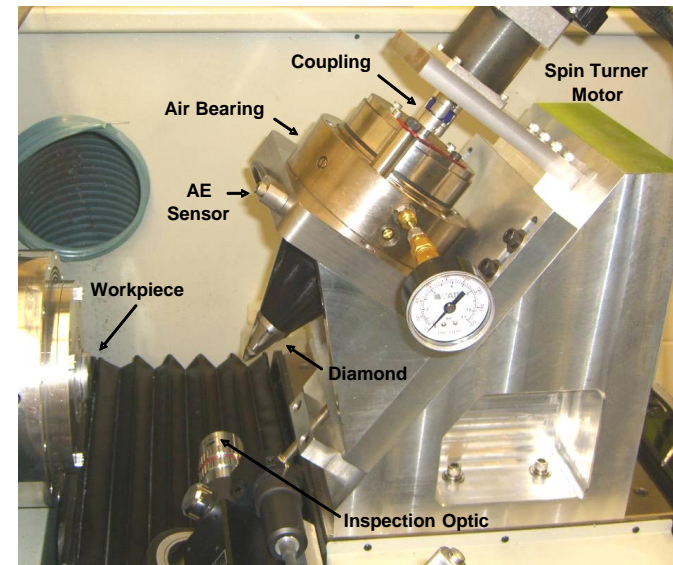


# Develop High MRR Process

- Spin turner integration
- Rotating at 1 Hz with an encoded servo-motor
- Developed mounting hardware



**LABVIEW GUI**



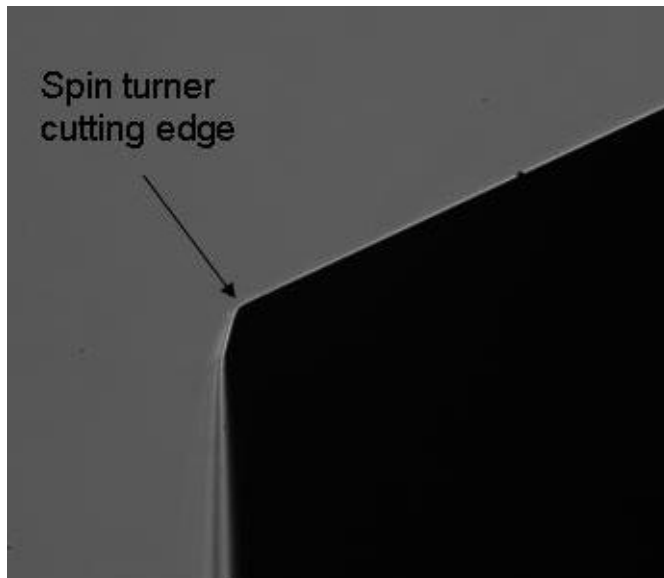
**Spin Turner Integration**

- Custom LABVIEW® GUI for data acquisition and system control
- Spin turner motor control
- Camera positioning, image acquisition, analysis
- Acoustic emissions data

# Tool Wear Measurement

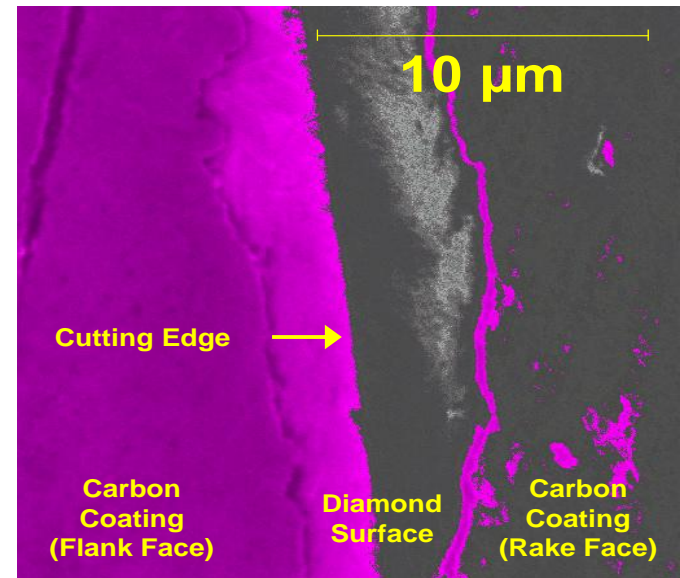
## Optical

- Integrated onto precision lathe
- Prosilica GC1600 camera
- 0.9  $\mu\text{m}$  resolution
- Controlled by MATLAB® GUI to photograph multiple locations after each cut



## SEM

- Thin carbon coating layer on tool prevents charge buildup
- Remove carbon coating from cutting edge
- Several measurements around cutting edge



## Shakedown Testing

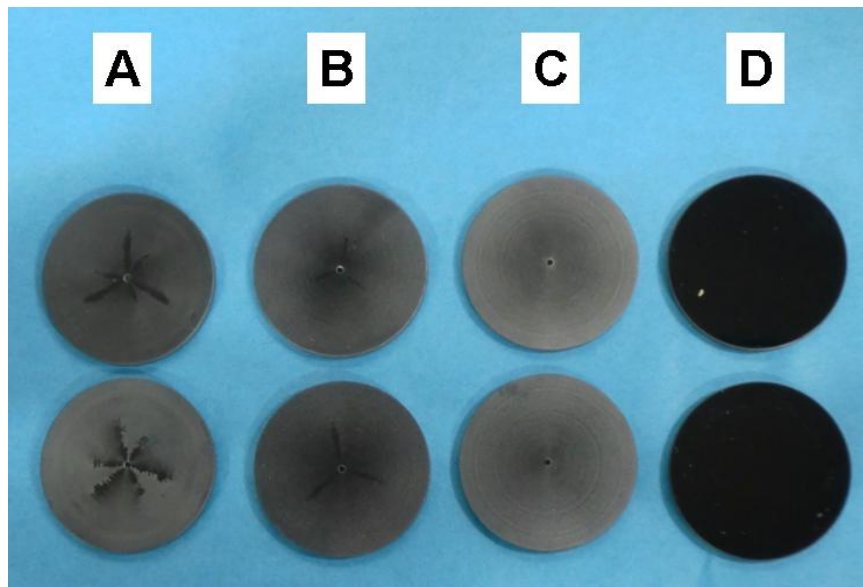
- **Single crystal silicon optics samples**
- **38 mm dia. x 3 mm thick**
- **Four optics for each condition**

<b>Cutting Condition</b>	<b>Depth of Cut (μm)</b>	<b>Feed Rate (μm)</b>	<b>Undeformed Chip Thickness (μm)</b>	<b>Total Cutting Depth(μm)</b>
A	3	3	0.25	36
B	6	6	0.70	36
C	12	12	2.0	36
D (uncut)	0	0	0	0

# Sample Disks Appearance

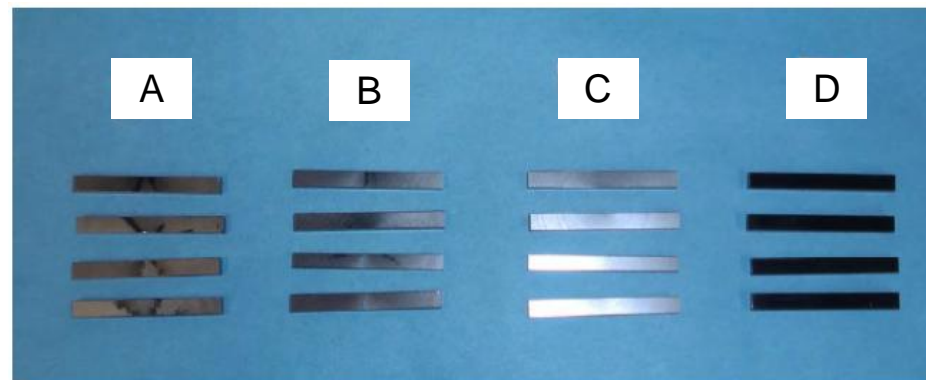
## Sample Disks

- Small depth of cut cases (A, B) show clear evidence of ductile to brittle transition depending on cutting orientation



## Modulus of Rupture Bars

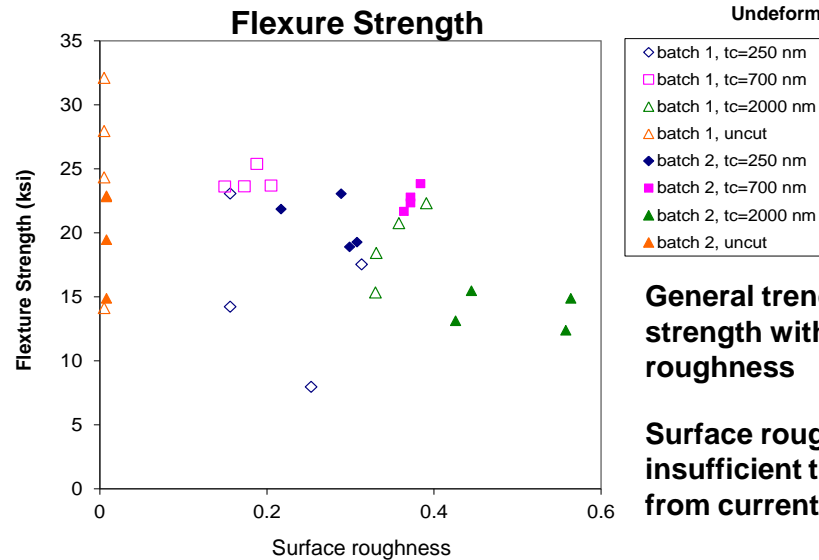
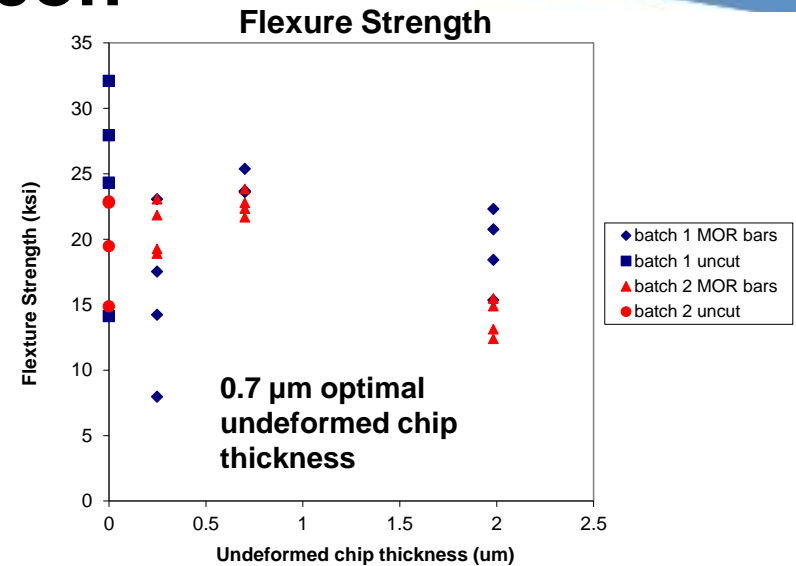
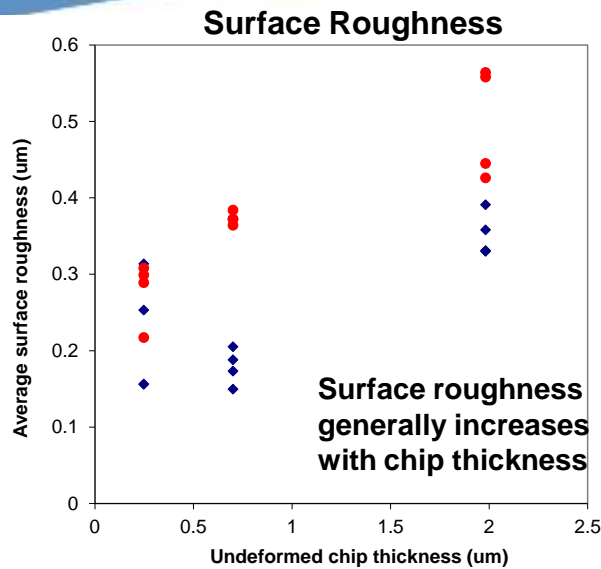
- 35 x 4 x 3 mm thick
- 2 bars per sample (32 total)
- Profilometry before strength testing



MOR Bars undergo 4-point bending failure test



# Results-Silicon



General trend of decreasing strength with increasing surface roughness

Surface roughness alone insufficient to predict strength from current data

# Summary of Technical Status

- Completed full integration and baseline testing of spin turner and tool measurement system
- Completed spin-turning tests of silicon and completed subsequent strength measurements
- Moving on to silicon carbide now
  - Repeat spin turning/strength tests
  - Refine single-point turning process
  - Optimize
  - Fabricate larger SiC mirror as final deliverable

Case	Surface Speed (m/s)	Depth of Cut ( $\mu\text{m}$ )	Feed Rate ( $\mu\text{m}/\text{rev}$ )	Undeformed Chip Thickness ( $\mu\text{m}$ )	Total Number of Cuts	Total Cutting Depth ( $\mu\text{m}$ )
A	0.5	3	3	0.25	12	36
B	0.5	6	6	0.70	6	36
C	0.5	12	12	2.00	3	36
D	N/A	0	0	0	0	0
E	2	6	6	0.70	6	36
F	2	12	12	2.00	3	36
G	2	12	12	2.00	12	144

# Questions